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				First Named Inventor	DeSimone	
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Signature Considered	

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Substitute for form 1449/PTO				Complete if Known		
(Revised 07/	(2007)			Application Number	10/583,570	
INEOD	MATION	DISCLO	STIDE	Filing Date	March 5, 2007	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				First Named Inventor	DeSimone	
				Art Unit	1791	
				Examiner Name	Not Yet Assigned	
Sheet	10	of	10	Attorney Docket Number	035052/338899	

		OTHER DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, strail, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	English Language Translation Attached
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